



US00D616391S

(12) **United States Design Patent**
Sato

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(45) **Date of Patent:** **** May 25, 2010**

(54) **PEDESTAL OF HEAT INSULATING
CYLINDER FOR MANUFACTURING
SEMICONDUCTOR WAFERS**

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(**) Term: **14 Years**

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(22) Filed: **Sep. 2, 2009**

(30) **Foreign Application Priority Data**

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(51) **LOC (9) Cl.** **13-03**

(52) **U.S. Cl.** **D13/182**

(58) **Field of Classification Search** D13/182;
206/454, 711; 118/728, 729; 211/41.18;
432/241, 253, 258

See application file for complete search history.

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(57) **CLAIM**

The ornamental design for a pedestal of heat insulating cylinder for manufacturing semiconductor wafers, as shown and described.

DESCRIPTION

FIG. 1 is front perspective view of a pedestal of heat insulating cylinder for manufacturing semiconductor wafers illustrating my new design;

FIG. 2 is a front view thereof;

FIG. 3 is a rear view thereof;

FIG. 4 is a right side view thereof;

FIG. 5 is a left side view thereof;

FIG. 6 is a top plan view thereof;

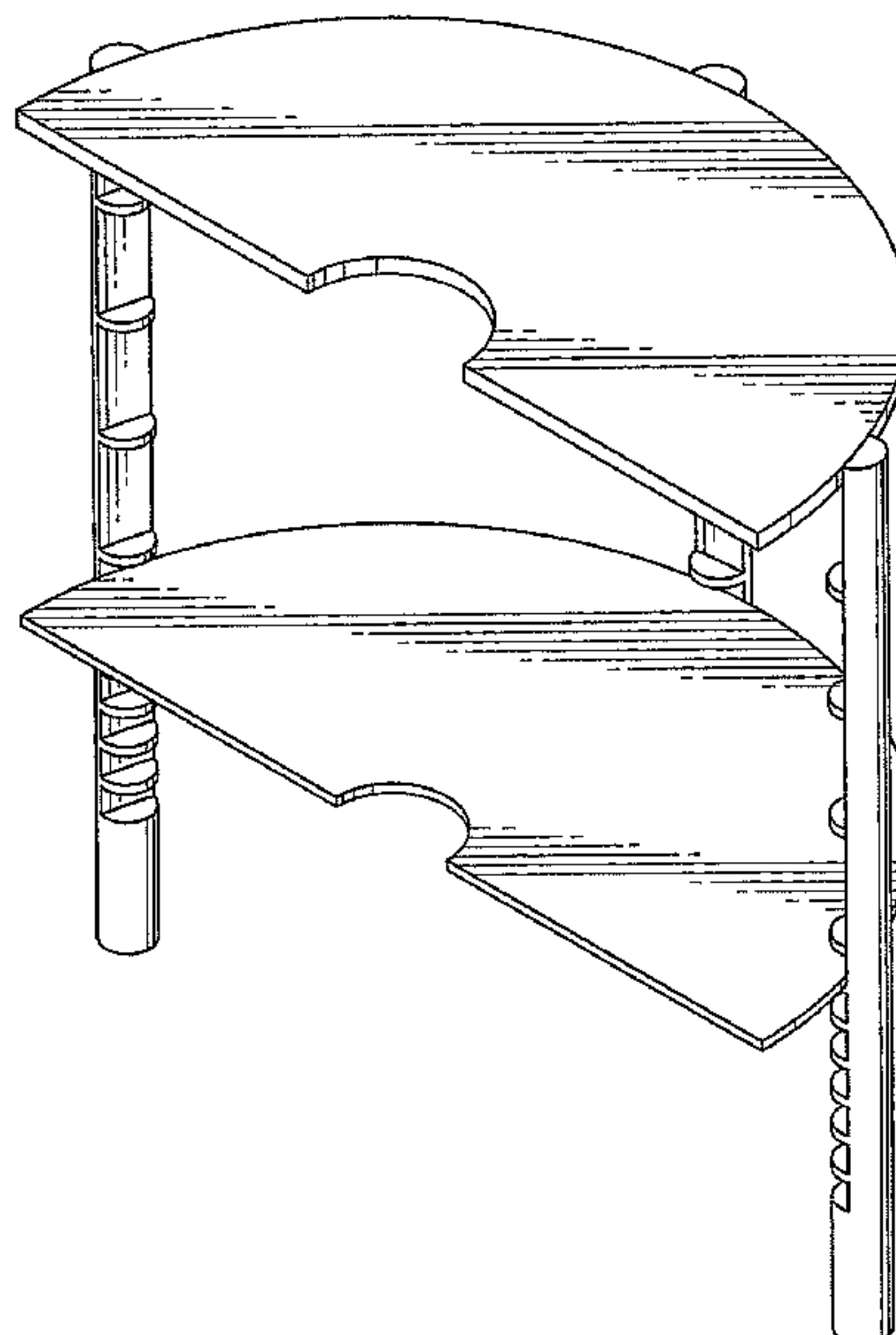
FIG. 7 is a bottom plan view thereof;

FIG. 8 is a cross-sectional view taken through line 8—8 of FIG. 2; and,

FIG. 9 is a front perspective view of a pedestal of heat insulating cylinder for manufacturing semiconductor wafers in use.

The broken lines are shown for illustrative purposes only and form no part of the claimed design.

1 Claim, 7 Drawing Sheets



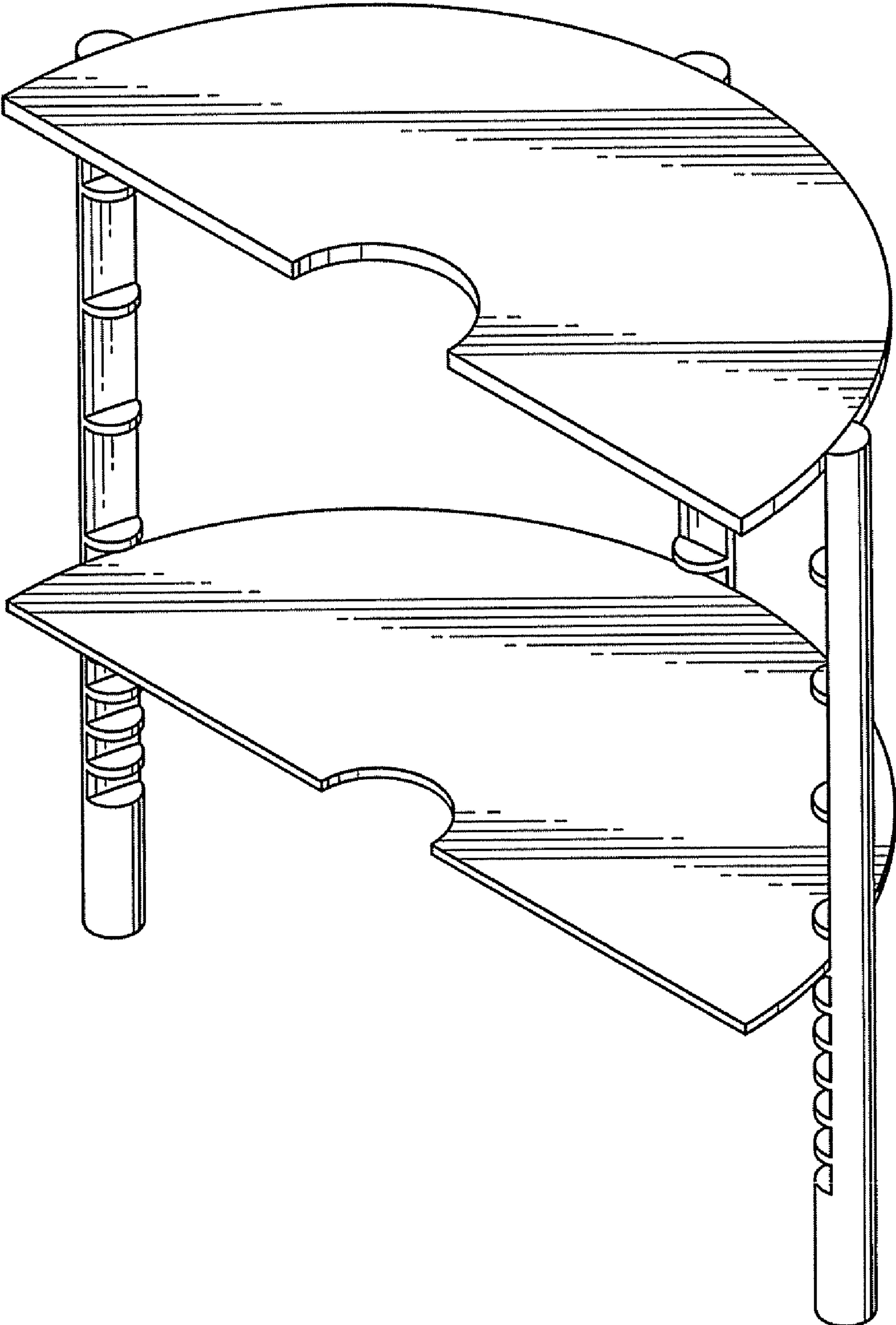


FIG. 1

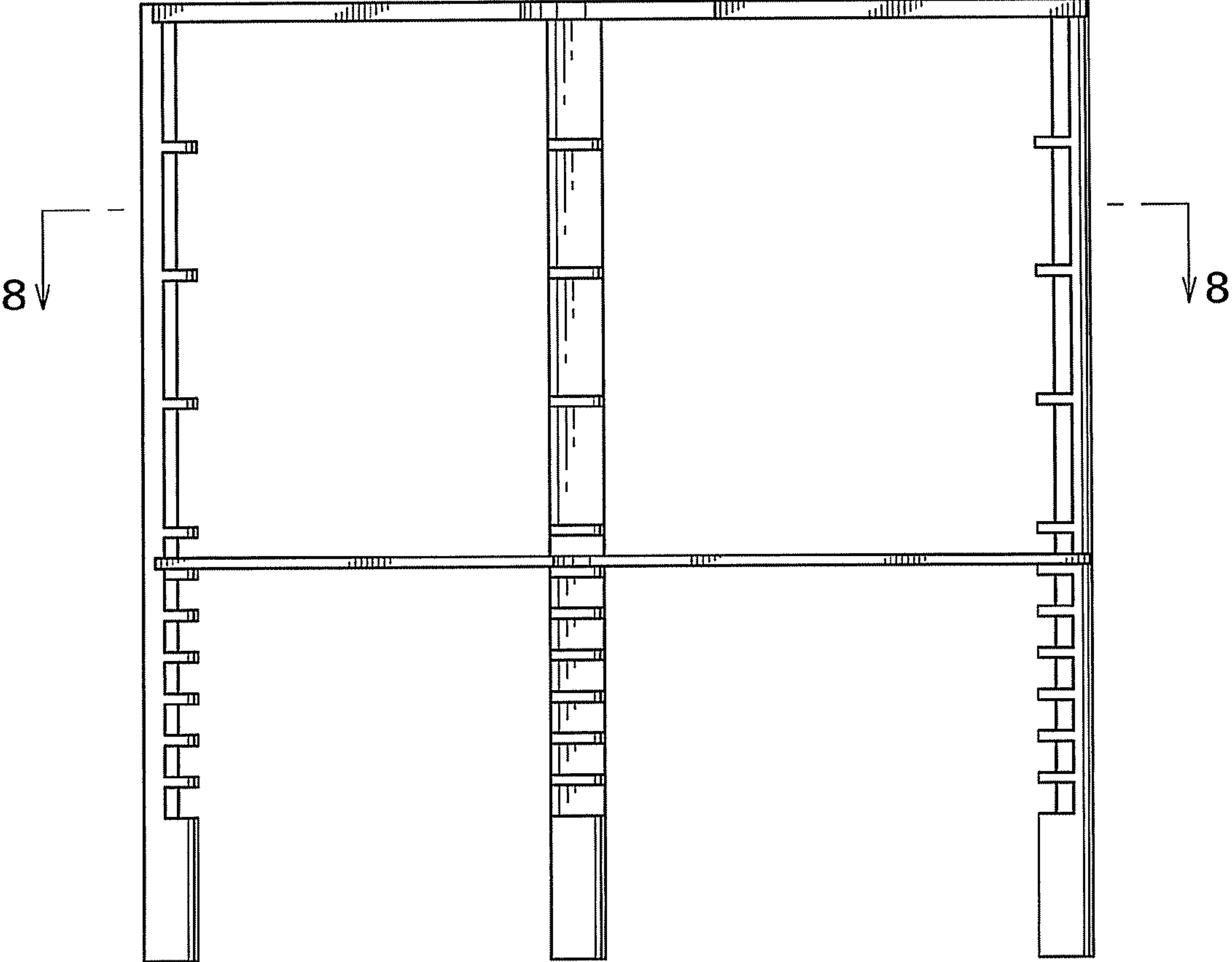


FIG. 2

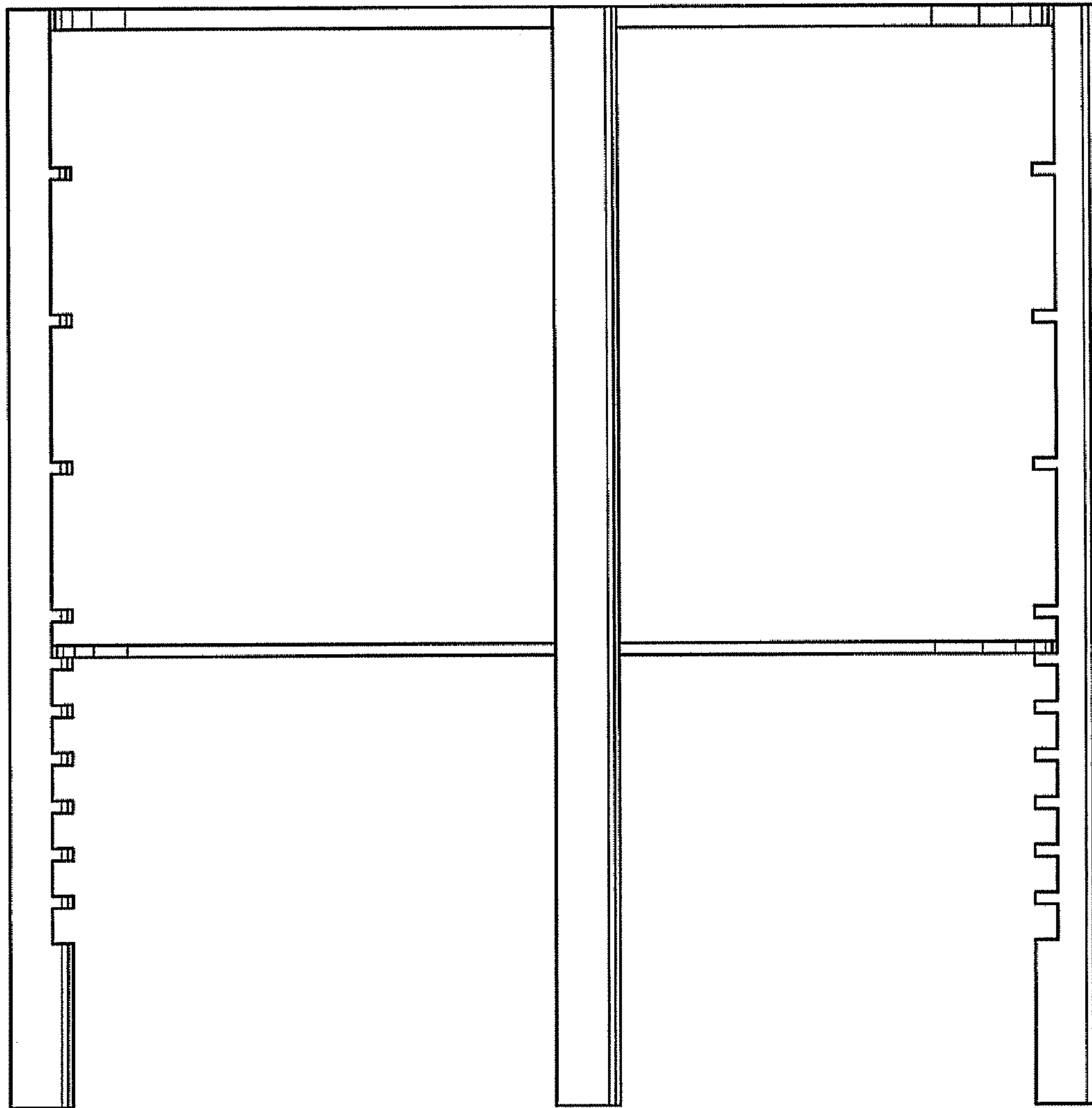


FIG. 3

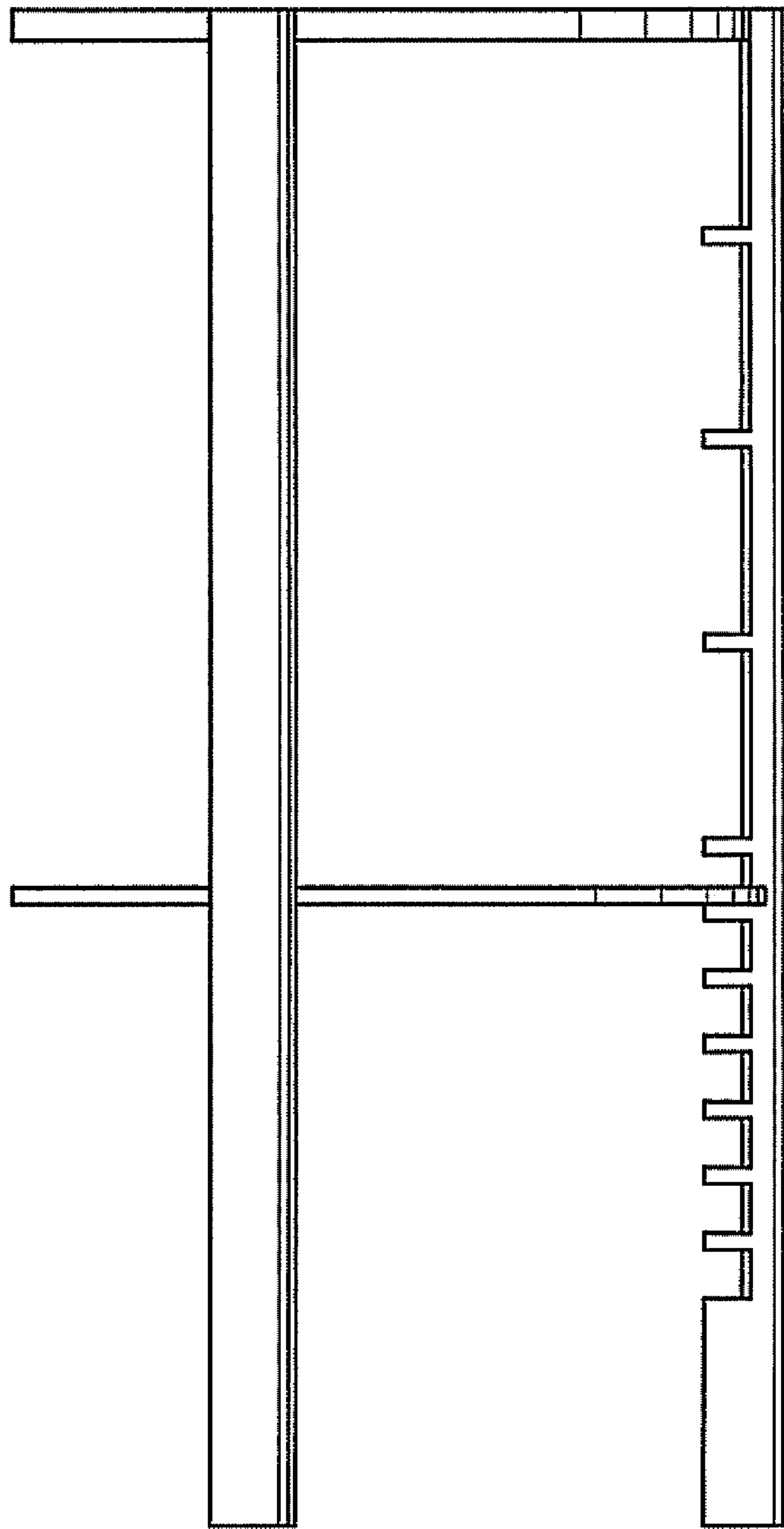


FIG. 4

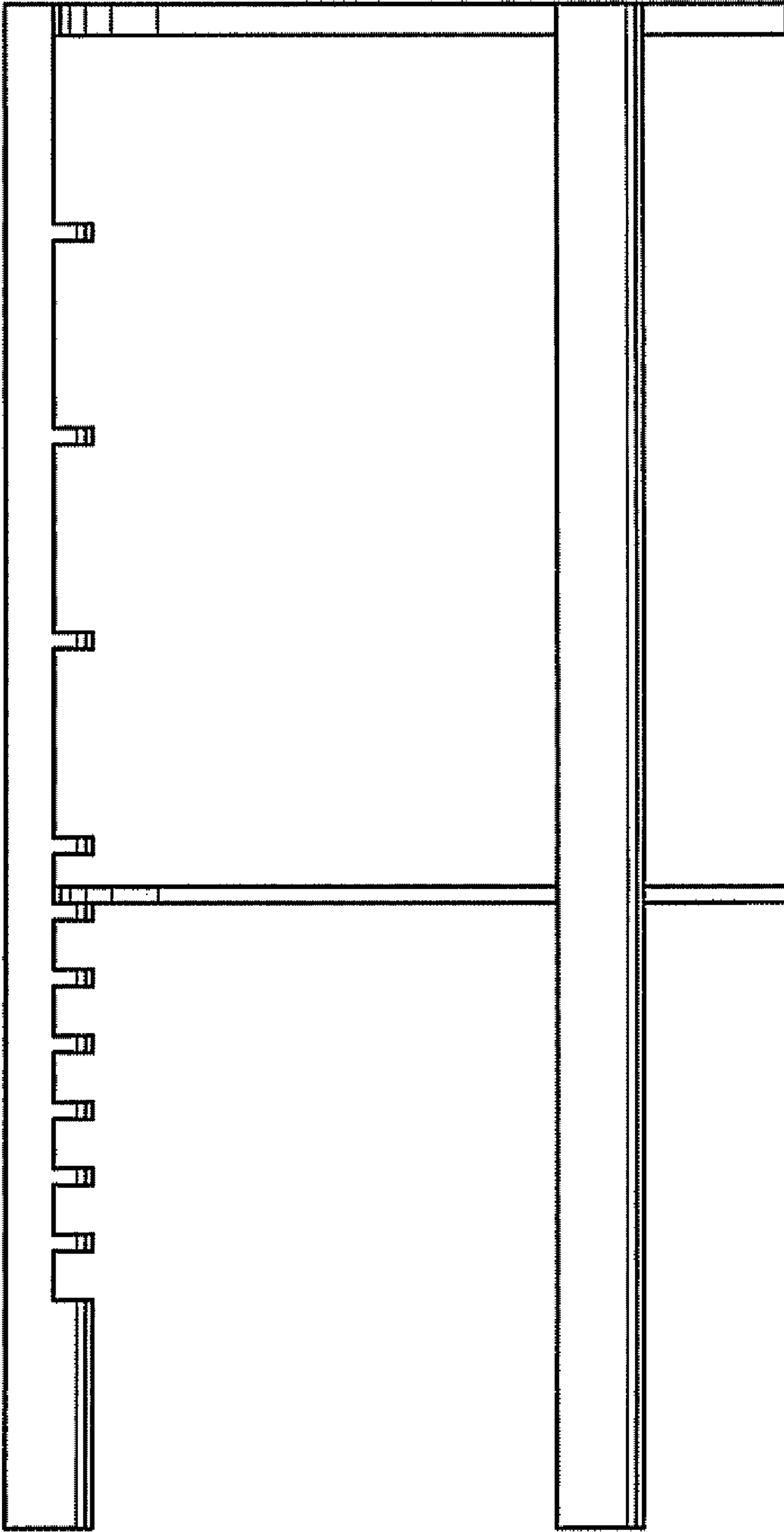


FIG. 5

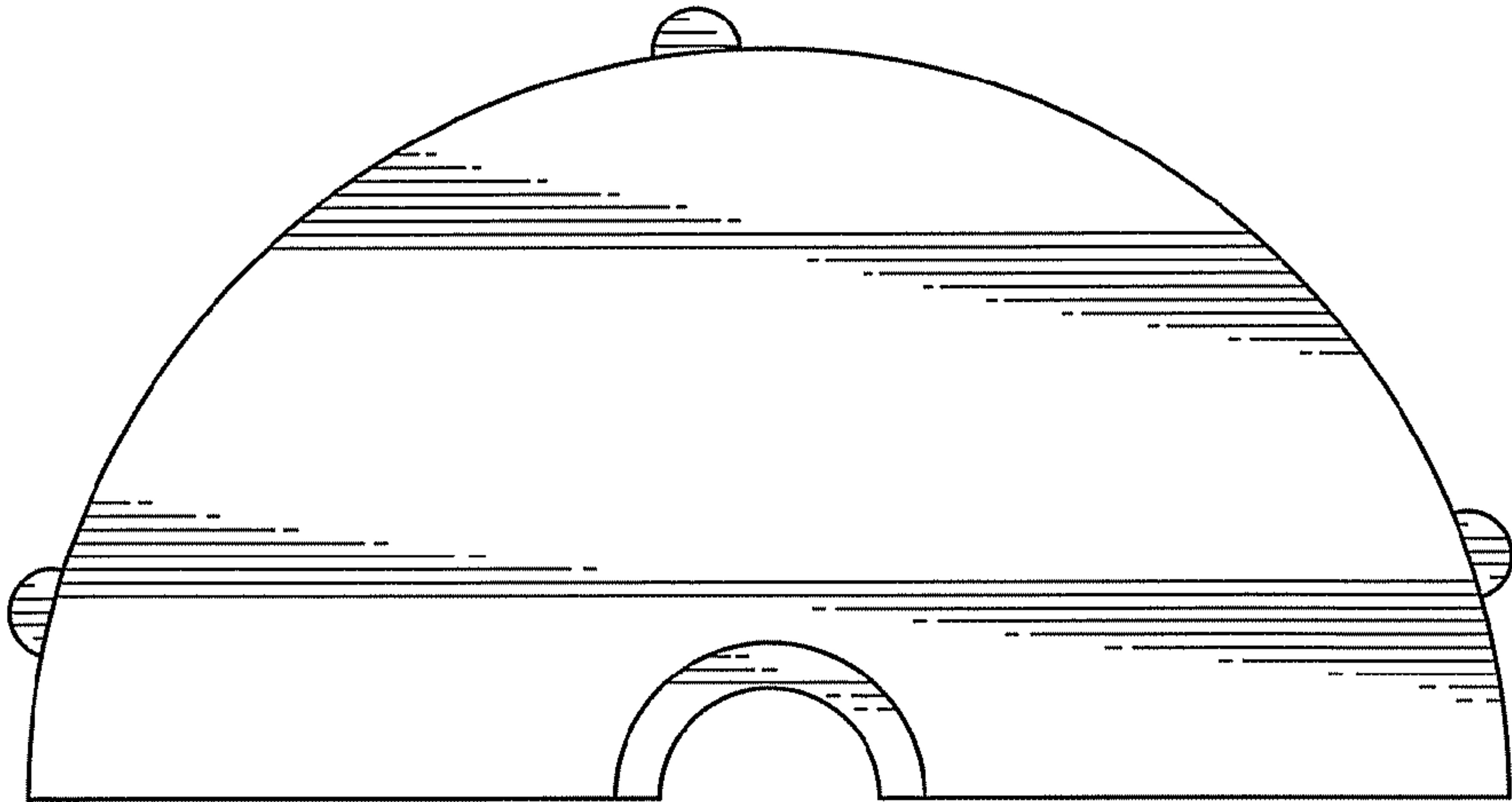


FIG. 6

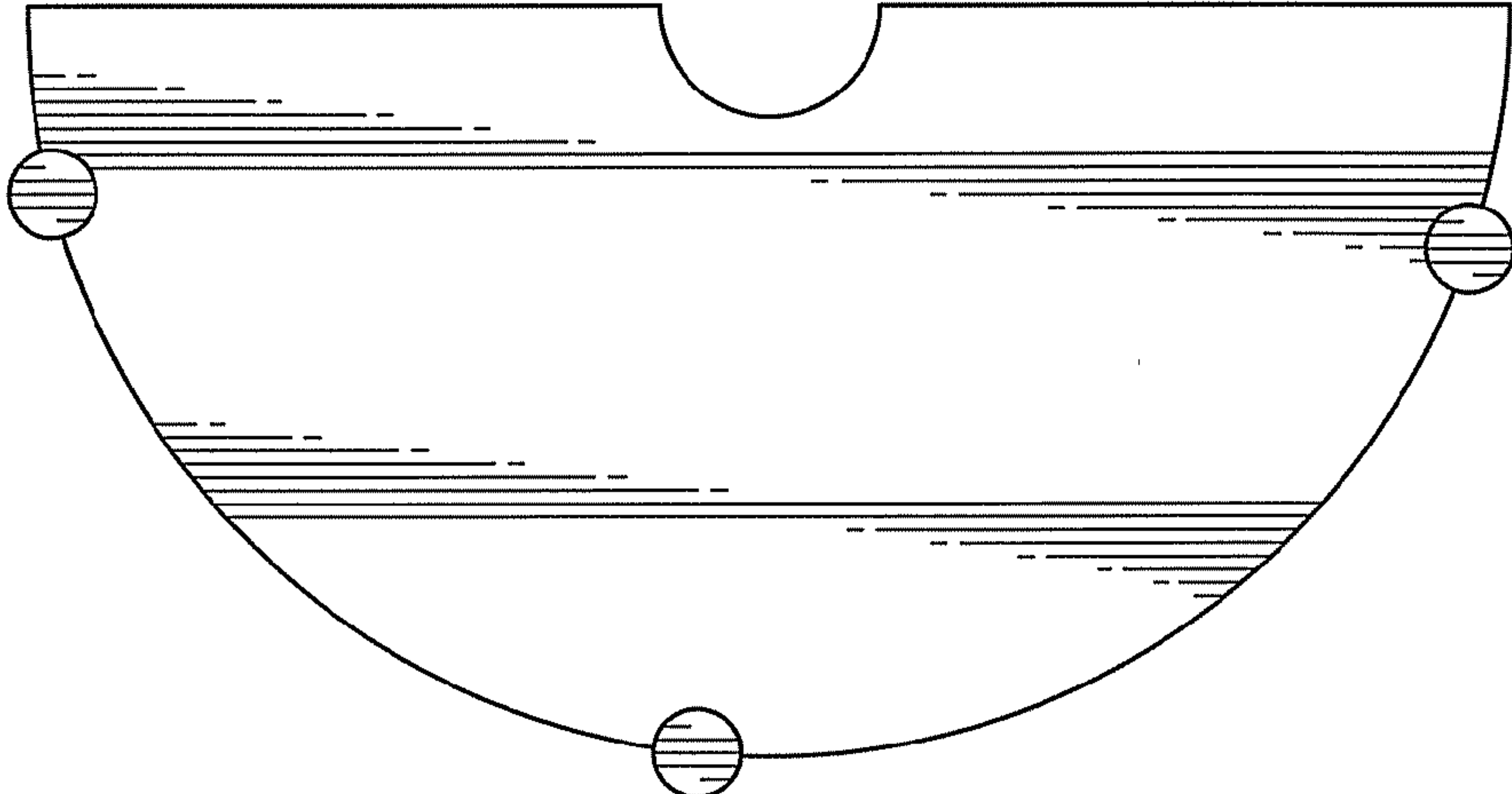


FIG. 7

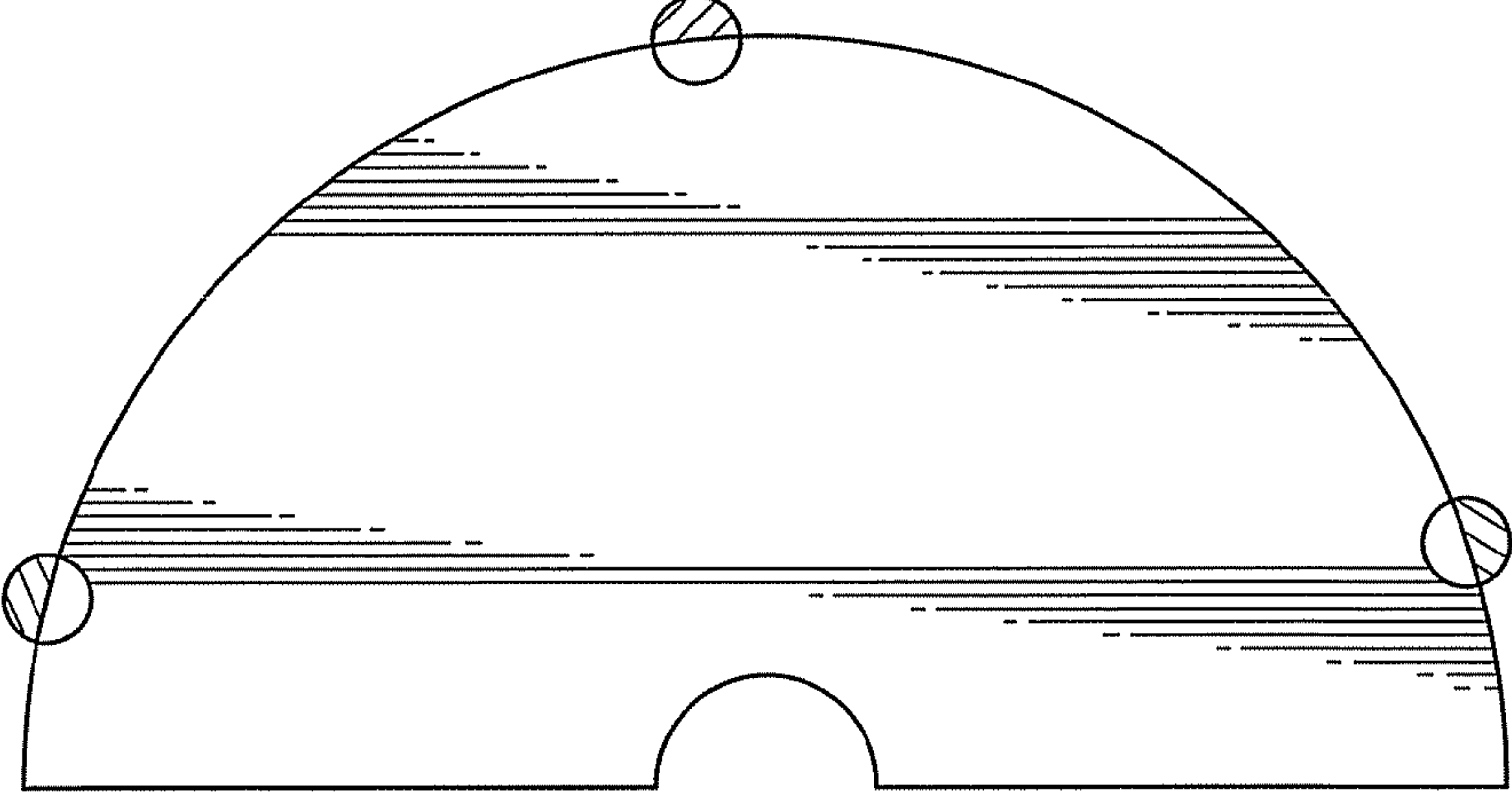


FIG. 8

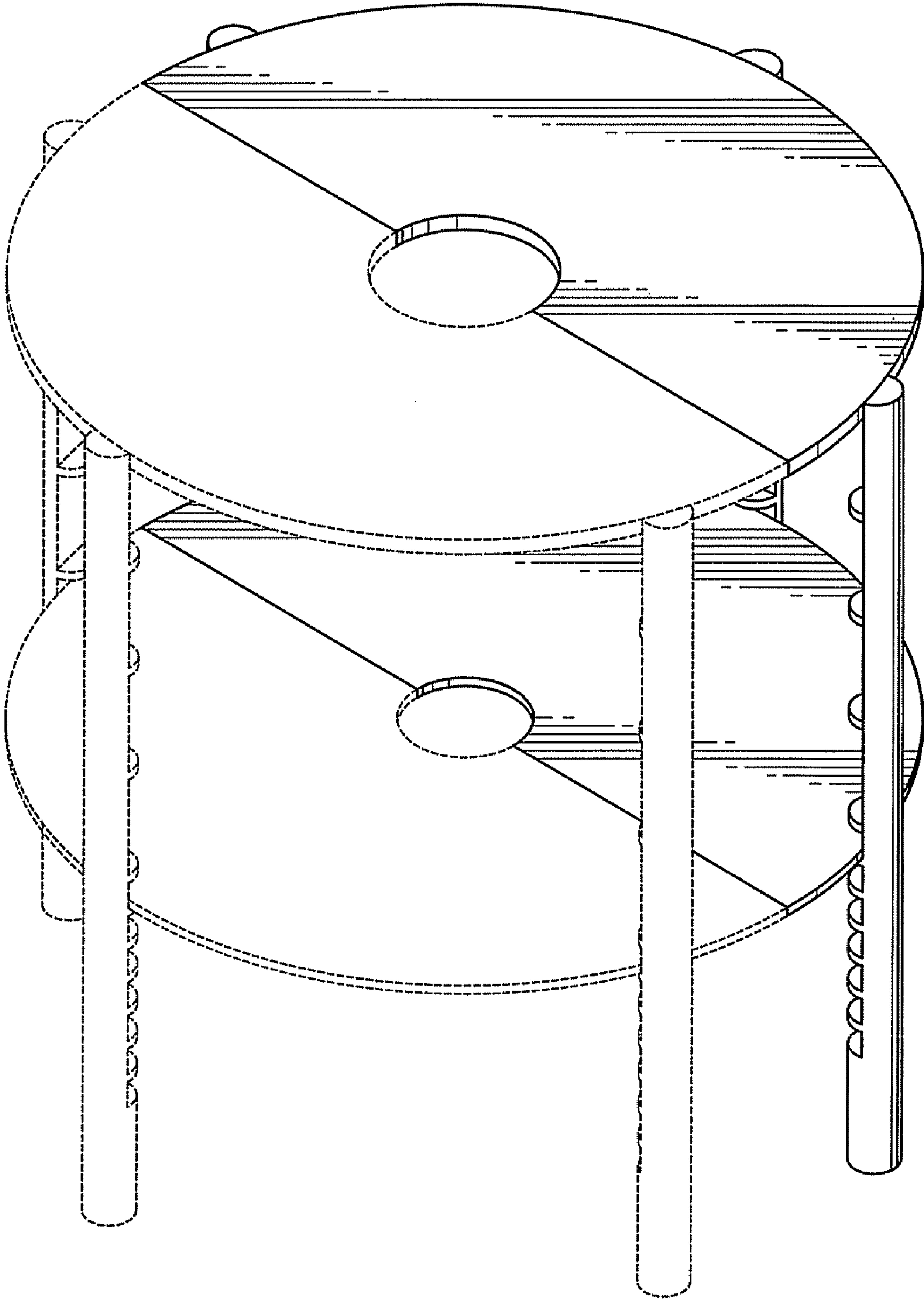


FIG. 9